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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Naoshi ADACHI et al.

Serial No.: 10/750,883

Filed: January 5, 2004

) ATTENTION AFTER FINAL PRACTICE

) EXPEDITED PROCESSING

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Art Unit: 2826

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Examiner: Williams, Alexander

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For: HEAT TREATMENT JIG FOR SEMICONDUCTOR SUBSTRATE AND METHOD OF  
HEAT TREATING SEMICONDUCTOR SUBSTRATE

AMENDMENT

Commissioner of Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Final Office Action dated March 13, 2007, Applicants request  
reconsideration of the final rejection of the claims. Please revise the claims as follows: